

METHOD AND APPARATUS FOR SUPPORTING A
SEMICONDUCTOR WAFER DURING PROCESSING
Granneman et al.
Appl. No.: Unknown Atty Docket: ASMINT.002C3

Fig - 1

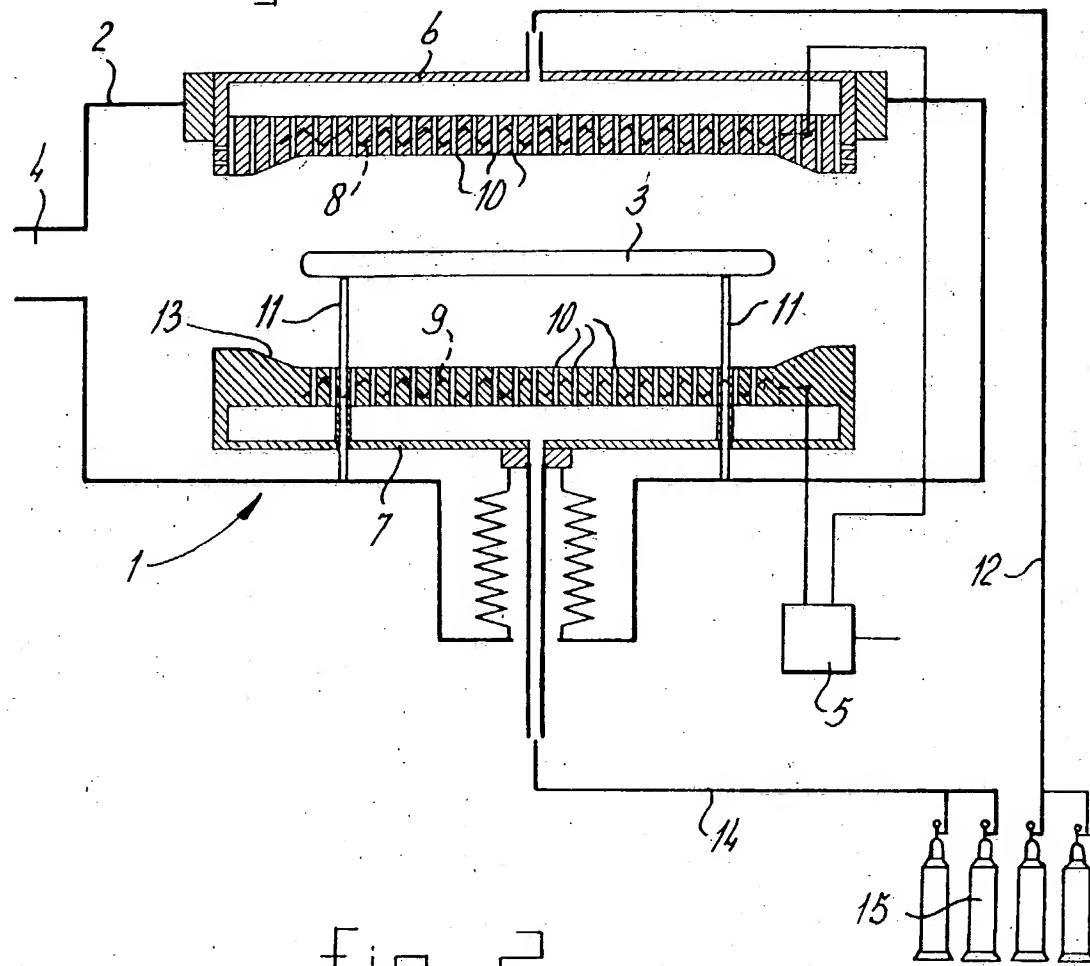
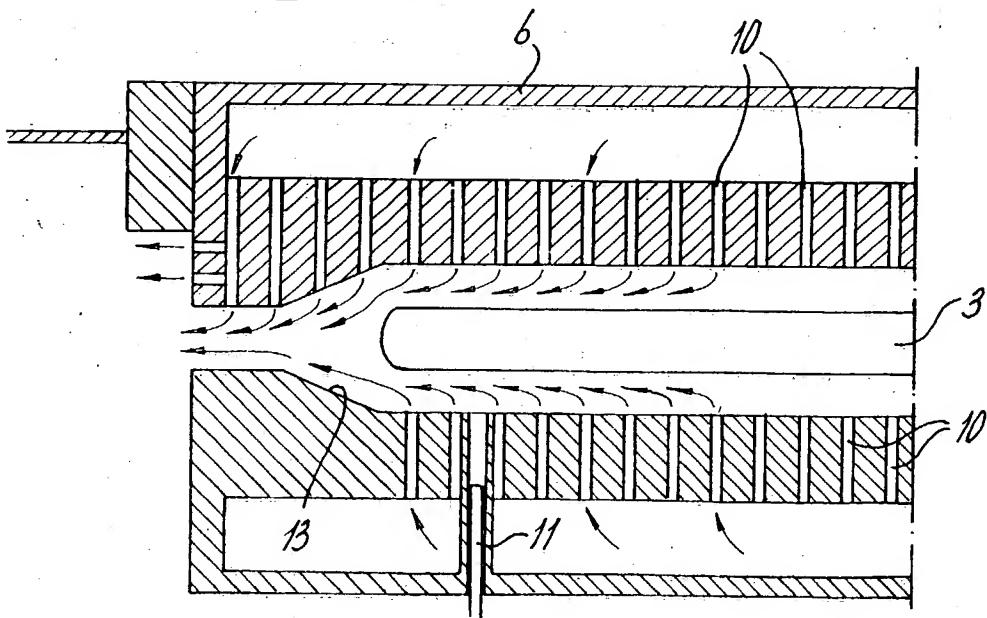


Fig - 2



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FIG - 3

